

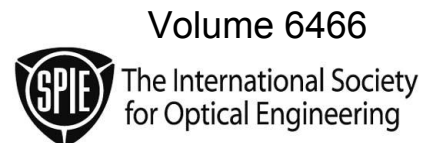
PROCEEDINGS OF SPIE

MOEMS and Miniaturized Systems VI

David L. Dickensheets
Bishnu P. Gogoi
Harald Schenk
Chairs/Editors

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